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APR 11 2006

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Leonel R. Arana et al.

Serial No.: 10/807,836

Filed: March 24, 2004

For: Microfabricated Hot Wire  
Vacuum Sensor§  
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Art Unit: 2813

Examiner: Heather Anne Doty

Docket: ITL 1133US  
P19113

Assignee: Intel Corporation

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450REPLY TO FINAL REJECTION

Sir:

In response to the final rejection mailed March 20, 2006, please amend the above-referenced patent application as follows:

Date of Deposit: April 11, 2006  
I hereby certify that this document is being facsimile transmitted to the United States Patent and Trademark Office (Fax No. 571/273-8300) on the date indicated above.

*Cynthia L. Hayden*  
Cynthia L. Hayden

OK to enter. H. Doty 4/17/06